Compare the Microscopes in detail

		High Voltage TEM JEM-1300NEF	**Atomic Resolution Analytical TEM** JEM-ARM200CF	**Cs-Corrected STEM/TEM** JEM-ARM200F	**3D tomography TEM** JEM-3200FSK	**Lorenz TEM** TECNAI G2-F20	**Digital TEM** TECNAI-20	**Holography TEM** HF-3300X	**Conventional TEM** JEM-2100HC	**Conventional TEM** JEM-2000EX	**Micro-Calorimeter FESEM** TES+ULTRA55	
Installation location		ITO Campus・CE20	ITO Campus・CE21	ITO Campus・CE21	ITO Campus・CE21	Chikushi Campus	ITO Campus・CE21	ITO Campus・CE21	ITO Campus・CE21	ITO Campus・CE21	ITO Campus・CE21	
Accelerating voltage		400,600,800,1000,1200	30,60,80,120,200	60,80,120,200	300	100-200	100-200	100,200,300	100,120,200	80-200	0.1-30	
Emission Gun		LaB6	C-FEG*2	T-FEG*1	T-FEG*1	T-FEG*1	LaB6	C-FEG*2	LaB6	W	T-FEG	
TEM resolution(nm)		0.12 point 0.10 lattice	0.11 point 0.10 lattice	0.11 point 0.10 lattice	0.26 point 0.14 lattice	0.24 point	0.24 point	0.14lattice	0.31 point 0.14 lattice	0.35 point	1.0-4.0 SEM　image	
STEM	minimum probe diameter	1.6 nm	0.1 nm	0.2 nm	4 nm	0.3 nm	2 nm	–	–	–	–	
	HAADF	–	○	○	–	○		–	–	–	–	
	ABF	–	○	○	–			–	–	–	–	
XEDS	type	SDD	SDD	SDD	Si(Li)	Si(Li)	Si(Li)	–	–	–	TES	Si
	solid angle	0.07 sr	2.0 sr	0.8 sr	0.22 sr	0.13 sr	0.13 sr	–	–	–	0.0022 sr	0.026 sr
	energy resolution	130 eV	130 eV	130 eV	140 eV		140 eV	–	–	–	20 eV	130 eV
EELS		Ω	Gatan Imaging Filter	Gatan Imaging Filter	Ω	–	–	Gatan Imaging Filter	–	–	–	
3D tomography		○	○	–	○	○	○	–	○	–	–	
Sample inclination angle		X:±70 Y:±20	X,Y:±25	X,Y:±25	X:±70 Y:±30	X:±80 Y:±30	X:±80 Y:±25	X:±15 Y:±15	X:±38 Y:±30	X:±45 Y:±30	T:-3～70 R:360	
Convergent electron diffraction		△	○	○	–	○	○	–	–	–	–	

*1　Thermal Field Emission Gun

*2　Cold Field Emission Gun